

Notice of References Cited			Application No. 09/437,135	Applicant(s) Yamazaki et al.		
			Examiner Erik Kielin	Group Art Unit 2813	Page 1 of 1	
U.S. PATENT DOCUMENTS						
*	DOCUMENT NO.	DATE	NAME		CLASS	SUBCLASS
A	5,153,701	10/1992	Roy		357	54
B						
C						
D						
E						
F						
G						
H						
I						
J						
K						
L						
M						
FOREIGN PATENT DOCUMENTS						
*	DOCUMENT NO.	DATE	COUNTRY	NAME	CLASS	SUBCLASS
x N	58-98933 A	6/1983	Japan	Maeda et al.	----	----
x O	60-187030	9/1985	Japan	Saito et al.	----	----
P						
Q						
R						
S						
T						
NON-PATENT DOCUMENTS						
*	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)					DATE
u	Ang et al. "Electrical characterization of low-pressure chemical-vapor-deposited silicon dioxide metal-oxide-silicon structures" Journal of Applied Physics 73(5), pp. 2397-2401.					3/1993
v	Wolf , et al., Silicon Processing for the VLSI Era, Vol. 1; Lattice Press: Sunset Beach, CA; pp. 57-58.					1986
w	Kepler, et al.; Chapter 5.9, "Rapid Thermal Annealing with the Heatpulse 210T RTA System" available at http://www-microlab.eecs.berkeley.edu:8080/manual/chap5.9					11/1991
x						

* A copy of this reference is not being furnished with this Office action.
(See Manual of Patent Examining Procedure, Section 707.05(a).)

FORM PTO-892
(REV. 2-92)U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

SERIAL NO.

08111522

GROUP ART UNIT

1104

ATTACHMENT
TO
PAPER
NUMBER

11

NOTICE OF REFERENCES CITED

APPLICANT(S)

YAMAZAKI ET AL

U.S. PATENT DOCUMENTS

•	DOCUMENT NO.	DATE	NAME	CLASS	SUB-CLASS	FILING DATE IF APPROPRIATE
A	5330929	7/19/94	PFISTER ET AL	437	200	10/5/92
B	5308998	5/13/94	YAMAZAKI ET AL	—	—	5/13/94
C	5313075	5/17/94	ZHANG ET AL	—	—	5/17/94
D	5278093	11/11/94	YONEMOTO	437	173	9/24/90
E	4784975	11/15/88	HOFFMAN ET AL	148	216.4	
F						
G						
H						
I						
J						
K						

FOREIGN PATENT DOCUMENTS

•	DOCUMENT NO.	DATE	COUNTRY	NAME	CLASS	SUB-CLASS	PERTINENT SHTS. PP. DWG. SPEC.
L							
M							
N							
O							
P							
Q							

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

R	
S	
T	
U	
EXAMINER	DATE
IRON RADIUS-1	11/18/94
	1 OF 2

* A copy of this reference is not being furnished with this office action.
(See Manual of Patent Examining Procedure, section 707.05 (a).)

BEST AVAILABLE COPY